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TRADEMARK OFFICE

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Mutsumi KIMURA

Application No.: 10/670,275

Filed: September 26, 2003 Docket No.: 117115

For: METHOD OF MANUFACTURING ELECTRO-OPTICAL DEVICE, ELECTRO-OPTICAL DEVICE, TRANSFERRED CHIP, TRANSFER ORIGIN SUBSTRATE, AND ELECTRONIC APPARATUS

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.

☒ 2. Relevance of the references is discussed in the present specification.

Respectfully submitted,

James A. Oliff
Registration No. 27,075

Joel S. Armstrong
Registration No. 36,430

JAO:JSA/tmw

Date: February 9, 2004

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

DEPOSIT ACCOUNT USE AUTHORIZATION
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Form PTO-1449 (REV. 8-83)	US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 117115	APPLICATION NO. 10/670,275
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		APPLICANT Mutsumi KIMURA	
		FILING DATE September 26, 2003	

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

	1	Shimoda et al, "Surface Free Technology by Laser Annealing (SUFTLA)", IEDM 99-289 pp 12.1.1-12.1.4
	2	Utsunomiya et al., "36.2: Low Temperature Poly-Si TFTs on Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA™), SID 00 DIGEST, pp 916-919
	3	Shimoda, "Future Trend of TFTs", Asia Display/IDW '01, pp 327-330
	4	Utsunomiya et al. "Low Temperature Poly Si TFT-LCD Transferred onto Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA®), Asia Display/IDW '01), pp 339-342
	5	Utsunomiya et al. "SUFTLA® (Surface Free Technology by Laser Ablation/Annealing), AM-LCD '02, pp 37-40

EXAMINER	DATE CONSIDERED

Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: February 9, 2004